IFKP

To: Complissioner for Patents
O. Box 1450
Alexandria, VA 22313-1450

Fr: Stephen B. Ackerman, Reg. No. 37,761

28 Davis Avenue

Poughkeepsie, N.Y. 12603

Subject:

Serial No.

10/786,807

02/25/2004

Apr. 2, 2008

H. M. CHEN

"METHOD FOR IMPROVING SEMICONDUCTOR WAFER TEST ACCURACY"

Grp. Art Unit: 2822

AU, BACH

## RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

In response to the Non-Final Office Action mailed Oct. 5, 2007, please amend the aboveidentified application for patent and consider the remarks, as follows:

## CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on Apr. 7, 2008.

Stephen B. Ackerman, Reg. No. 37,761

Signature

Date April 7,200

MEG-02-005

Amendments to the Claims are reflected in the listing of the Claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 6 of this paper.